

## UNITED STATES PATENT AND TRADEMARK OFFICE

UNITED STATES DEPARTMENT OF COMMERCE United States Patent and Trademark Office Address: COMMISSIONER FOR PATENTS P.O. Box 1450 Alexandria, Virginia 22313-1450 www.uspto.gov

## \*BIBDATASHEET\*

Bib Data Sheet

**CONFIRMATION NO. 2494** 

|  | <b></b>   |                           | <del></del>      |  | ···                          |                                  | <del></del> |             |
|--|---|---------------------------|------------------|--|------------------------------|----------------------------------|-------------|-------------|
| SERIAL NUMBER<br>09/913,334  | FILING DATE<br>08/13/2001<br>RULE   | CLASS<br>438              |                  | GROUP ART UNIT<br>2823                                 |                              | ATTORNEY DOCKET<br>NO.<br>110386 |             |             |
| APPLICANTS   |   |                           |                  |  |                              |                                  | ,           |             |
| Seiichi Miyazaki, ł  | Kosyoku-shi, JAPAN;   |                           |                  |  |                              |                                  |             |             |
| ** CONTINUING DATA ** This application is  ** FOREIGN APPLICATION  JAPAN 11-374052   | a 371 of PCT/JP00/09185   | 5 12/25/200               | 00               |  |                              |                                  |             |             |
| Foreign Priority claimed  35 USC 119 (a-d) conditions met yes no Met after Allowance  Verified and Acknowledged Examiner's Signature |   |                           | STATE OR         | SHEETS   |                              | тс                               | TAL         | INDEPENDENT |
|  |   |                           | COUNTRY<br>JAPAN | DR   |                              |                                  | AIMS<br>22  | CLAIMS<br>7 |
| ADDRESS<br>25944<br>OLIFF & BERRIDGE, PL<br>P.O. BOX 19928<br>ALEXANDRIA , VA<br>22320   | С   |                           |                  |  |                              |                                  |             |             |
| TITLE<br><del>Etchant,</del> etching method-   | FDR<br><del>and</del> semiconductor silicon                                       | WAFE<br><del>waffer</del> | R                |  |                              |                                  |             |             |
|  |   |                           |                  |  | All Fees  1.16 Fees (Filing) |                                  |             |             |
| No.  | Authority has been given in Paper to charge/credit DEPOSIT ACCOUNT for following: |                           |                  | 1.17 Fees (Processing Ext. of time)  1.18 Fees (Issue) |                              |                                  |             |             |
|  |   |                           |                  | Other  |                              |                                  |             |             |
|  |   |                           |                  |  | ☐ Credit                     |                                  |             |             |